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FIRST NAMED INVENTOR ATTORNEY DOCKET NO. CONFIRMATION NO. APPLICATION NO. FILING DATE 02/12/2001 Atsuomi Inukai 108573 8148 09/780,423 **EXAMINER** 25944 7590 12/16/2003 OLIFF & BERRIDGE, PLC PIZIALI, JEFFREY J P.O. BOX 19928 PAPER NUMBER ART UNIT ALEXANDRIA, VA 22320 2673

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)
Office Action Summary	09/780,423	INUKAI, ATSUOMI
	Examiner	Art Unit
	Jeff Piziali	2673
The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply		
A SHORTENED STATUTORY PERIOD FOR REP THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a re - If NO period for reply is specified above, the maximum statutory perio - Failure to reply within the set or extended period for reply will, by statu - Any reply received by the Office later than three months after the mail earned patent term adjustment. See 37 CFR 1.704(b). Status	I. 1.136(a). In no event, however, may a repeply within the statutory minimum of thirty will apply and will expire SIX (6) MONT ute, cause the application to become ABA	ply be timely filed (30) days will be considered timely. HS from the mailing date of this communication. NDONED (35 U.S.C. § 133).
1) Responsive to communication(s) filed on <u>03</u>	November 2003.	
2a) ☐ This action is FINAL . 2b) ☑ Thi	is action is non-final.	
3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.		
Disposition of Claims		
4) Claim(s) 1-20 is/are pending in the application 4a) Of the above claim(s) is/are withdr 5) Claim(s) is/are allowed. 6) Claim(s) 1-20 is/are rejected. 7) Claim(s) is/are objected to. 8) Claim(s) are subject to restriction and application Papers 9) The specification is objected to by the Examination The drawing(s) filed on 12 February 2001 is/a Applicant may not request that any objection to the Replacement drawing sheet(s) including the corresponding to the corresponding the correspondin	rawn from consideration. /or election requirement. ner. are: a)⊠ accepted or b)□ of the drawing(s) be held in abeyand	ee. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d). 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.		
Priority under 35 U.S.C. §§ 119 and 120		
12) △ Acknowledgment is made of a claim for foreign a) △ All b) ☐ Some * c) ☐ None of: 1. △ Certified copies of the priority document a. ☐ Copies of the certified copies of the priority document a. ☐ Copies of the certified copies of the priority document application from the International Bure * See the attached detailed Office action for a list also ☐ Acknowledgment is made of a claim for domest since a specific reference was included in the factorist and ☐ The translation of the foreign language per 14) ☐ Acknowledgment is made of a claim for domest reference was included in the first sentence of	nts have been received. nts have been received in Apionity documents have been reau (PCT Rule 17.2(a)). st of the certified copies not restic priority under 35 U.S.C. § first sentence of the specifical provisional application has bestic priority under 35 U.S.C. §	eceived in this National Stage eceived. 119(e) (to a provisional application) tion or in an Application Data Sheet. en received. 18 120 and/or 121 since a specific
Attachment(s)		
	5) Notice of Inf	mmary (PTO-413) Paper No(s) ormal Patent Application (PTO-152)

U.S. Patent and Trademark Office PTOL-326 (Rev. 11-03)

Art Unit: 2673

DETAILED ACTION

Continued Examination Under 37 CFR 1.114

1. A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 3 November 2003 has been entered.

Priority

2. Receipt is acknowledged of papers submitted under 35 U.S.C. 119(a)-(d), which papers have been placed of record in the file.

Claim Rejections - 35 USC § 102

3. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(e) the invention was described in a patent granted on an application for patent by another filed in the United States before the invention thereof by the applicant for patent, or on an international application by another who has fulfilled the requirements of paragraphs (1), (2), and (4) of section 371(c) of this title before the invention thereof by the applicant for patent.

The changes made to 35 U.S.C. 102(e) by the American Inventors Protection Act of 1999 (AIPA) and the Intellectual Property and High Technology Technical Amendments Act of 2002 do not apply when the reference is a U.S. patent resulting directly or indirectly from an

Art Unit: 2673

international application filed before November 29, 2000. Therefore, the prior art date of the reference is determined under 35 U.S.C. 102(e) prior to the amendment by the AIPA (pre-AIPA 35 U.S.C. 102(e)).

4. Claims 1-4 and 7-15 are rejected under 35 U.S.C. 102(e) as being anticipated by Maeda (US 6,512,510).

Regarding claim 1, Maeda discloses a pointing device [Figs. 1 & 3; P1] including: a sensor substrate [Fig. 3; 8] having a flat board form; a stick member [Fig. 3; 2] vertically provided on an upper surface of the sensor substrate; at least a pair of strain sensors [Fig. 3; 9a & 9c] arranged in symmetrical relation to each other with respect to the stick member; and a slit [Fig. 3; 6 & 8d] formed on the sensor substrate near the strain sensor, the slit remaining on the sensor substrate and having parallel slit portions which are provided at both sides of each of the strain sensors to form an intersecting area [Fig. 3; 4a-4d] of the sensor substrate between the parallel slit portions; wherein the slit induces an increase in an amount of deformation generated in the intersecting area of the sensor substrate during operation of the stick member (see Column 5, Line 34 - Column 6, Line 64).

Regarding claim 2, Maeda discloses the sensor substrate is made of a flexible insulative material (see Column 5, Lines 61-65).

Art Unit: 2673

Regarding claim 3, Maeda discloses the strain sensor is made of a resistive material which changes its resistance value with stress applied to the strain sensor (see Column 5, Line 66 - Column 6, Line 64).

Regarding claim 4, Maeda discloses the resistance material is formed adhering onto the insulative material by a layer forming technique (see Column 5, Line 66 - Column 6, Line 31).

Regarding claim 7, Maeda discloses another pair of strain sensors [Fig. 3; 9b & 9d] arranged on the sensor substrate in a direction [Fig. 3; Y1] perpendicular to a line [Fig. 3; X1] connecting the first pair of strain sensors while passing through a center of the stick member, wherein the strain sensors are arranged at 90 degree angular intervals around the stick member (see Column 6, Lines 1-64).

Regarding claim 8, Maeda discloses the slit portions formed between the strain sensors adjacently arranged are connected to form the slit in an L-shape (see Fig. 3; Column 5, Lines 39-65).

Regarding claim 9, Maeda discloses four L-shaped slits are formed at 90 degree angular intervals around the stick member, and the four L-shaped slits jointly form a cross-shaped intersecting area (see Fig. 3; Column 5, Line 39 - Column 6, Line 3).

Art Unit: 2673

Regarding claim 10, Maeda discloses chip resistances [Fig. 3; 10] capable of being trimmed, connected in series with the strain sensors correspondingly and arranged out of the intersecting area on the sensor substrate (see Column 6, Lines 1-31).

Regarding claim 11, Maeda discloses a strain detecting substrate section [Fig. 3; 4a-4d] on which the stick member and the strain sensors are disposed, this section being used for detecting an amount of strain of the sensor substrate by means of the strain sensors, the strain being caused by operation of the stick member; and a signal processing substrate section [Fig. 3; 9a-9d & 10] for signal processing the strain amount of the sensor substrate detected by the strain detecting substrate section; wherein the strain detecting substrate section and the signal processing substrate section are connected through a connecting substrate section [Fig. 2; 8c] which is narrower in width than the sensor substrate (see Column 5, Line 54 - Column 6, Line 64).

Regarding claim 12, Maeda discloses the connecting substrate section is produced by formation of cut-out portions from both sides of the sensor substrate in its width direction toward a center thereof (see Figs. 2 & 3; Column 5, Line 54 - Column 6, Line 64).

Regarding claim 13, Maeda discloses an engagement member portion [Fig. 3; 3] protruding from a lower end of the stick member; an attachment hole [Fig. 3; 8a] formed in the sensor substrate, in which the engagement portion is inserted; and a fixing member [Fig. 3; 12] for fixing the engagement portion of the stick member inserted in the attachment hole, the fixing

Art Unit: 2673

member being attached from a back surface of the sensor substrate; wherein the stick member is vertically provided on the sensor substrate in an engagement relation thereto (see Fig. 3; Column 6, Lines 13-31).

Regarding claim 14, this claim is rejected by the reasoning applied in the above rejection of claim 1, furthermore Maeda discloses a keyboard [Fig. 1] provided with a plurality of keys [Fig. 1; 27] arranged on a keyboard substrate and a pointing device [Fig. 1; P1] mounted on a part of an operating face of the keyboard (see Column 1, Line 15 - Column 2, Line 41).

Regarding claim 15, this claim is rejected by the reasoning applied in the above rejection of claims 1 and 14, furthermore Maeda discloses a controller [i.e. computer] for controlling various data [i.e. signals] input with the keys on the keyboard; and a display [i.e. inherent for cursor display] for displaying the data [i.e. cursor signals] under control by the controller (see Column 1, Line 41 - Column 2, Line 28).

Claim Rejections - 35 USC § 103

- 5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 6. Claims 5 and 6 are rejected under 35 U.S.C. 103(a) as being unpatentable over Maeda et al. (US 6,512,510).

Art Unit: 2673

Regarding claim 5, Maeda does not expressly disclose the layer forming technique is selected from among a vacuum deposition method, a sputter method, and a vapor phase deposition method. However, such layer forming techniques were well known and commonly understood at the time of invention. Therefore, it would have been obvious to one skilled in the art at the time of invention to use a vacuum deposition method, a sputter method, or a vapor phase deposition method as Maeda's layer forming technique, so as to form the resistance material adhering to the insulative material using traditionally appropriate and operationally successful layering methods.

Regarding claim 6, Maeda does not expressly disclose the resistance material is mainly composed of carbon. However, resistance materials made mainly of carbon were well known and commonly understood at the time of invention. Therefore, it would have been obvious to one skilled in the art at the time of invention to use mainly carbon as Maeda's resistance material, so as to compose the resistance material using a operationally appropriate and commonly available material.

7. Claims 16-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Maeda et al. (US 6,512,510) in view of the present application's own admission of prior art.

Regarding claim 16, Maeda does not expressly disclose each of the strain sensors is formed with a plurality of windows in which the resistance material is absent, the windows being arranged in aligned relation to a line connecting the pair of strain sensors while passing through a center of the stick member, and also each of the strain sensors is formed with a notch which is

Art Unit: 2673

made by a trimming process of irradiating a laser beam to the strain sensor along the alignment direction of the windows.

However, the present application discloses, as prior art, forming strain sensors [Fig. 14; 153] with a plurality of windows in which the resistance material is absent, the windows being arranged in aligned relation to a line connecting the pair of strain sensors while passing through a center of the stick member, and also each of the strain sensors is formed with a notch [Fig. 14, 153a] which is made by a trimming process of irradiating a laser beam to the strain sensor along the alignment direction of the windows (see Figs. 14 & 15; Page 2, Line 21 - Page 3, Line 27). Maeda and the present application's prior art disclosure are analogous art, because they are from the shared field of strain sensing pointing devices. Therefore, it would have been obvious to one skilled in the art at the time of invention to use such a strain sensor formation as Maeda's strain sensor circuitry, so as to prevent the inconsistency in an offset voltage outputted due to the sensors.

Regarding claim 17, the present application discloses, as prior art, the trimming process making the notch so that an endpoint of the notch is received within the window (see Figs. 14 & 15; Page 2, Line 21 - Page 3, Line 27).

Regarding claim 18, Maeda does not expressly disclose that the resistance material is formed adhering onto the insulative material by a thick layer printing technique. However, such a layer forming method was well known and commonly understood at the time of invention.

Therefore, it would have been obvious to one skilled in the art at the time of invention to use a

Art Unit: 2673

thick layer printing technique as Maeda's layer forming method, so as to form the resistance material adhering to the insulative material using a traditionally appropriate and operationally successful layering method.

Regarding claim 19, Maeda does not expressly disclose that the resistance material is a ruthenium material. However, resistance materials made from ruthenium materials were well known and commonly understood at the time of invention. Therefore, it would have been obvious to one skilled in the art at the time of invention to use ruthenium material as Maeda's resistance material, so as to compose the resistance material using a operationally appropriate and commonly available material.

Regarding claim 20, Maeda does not expressly disclose the ruthenium material is ruthenium dioxide. However, resistance materials made ruthenium dioxide were well known and commonly understood at the time of invention. Therefore, it would have been obvious to one skilled in the art at the time of invention to use ruthenium dioxide as Maeda's resistance material, so as to compose the resistance material using a operationally appropriate and commonly available material.

Response to Arguments

8. Applicant's arguments with respect to claims 1-20 have been considered but are moot in view of the new grounds of rejection.

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Jeff Piziali whose telephone number is (703) 305-8382. The examiner can normally be reached on Monday - Friday (6:30AM - 3PM).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Bipin Shalwala can be reached on (703) 305-4938. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9314.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 305-4700.

11 December 2003

BIPIN SHALWALA SUPERVISORY PAYENT EXAMINER TECHNOLOGY CENTER 2600